

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L4	26	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and @ay<="2003"	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:11
L6	920673	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and @ay<="2003" laminat\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:15
L7	5	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and @ay<="2003" and laminat\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:15
L8	8	semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and laminat\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:18
L9	0	257/40-666 and (semiconduct\$3 adj laser and metal adj (layer film material) and above and under and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and laminat\$3).clm.	US-PGPUB	OR	OFF	2008/07/06 12:22
L10	0	257/40-666 and (semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and laminat\$3).clm.	US-PGPUB	OR	OFF	2008/07/06 12:22
L11	1	"257".clas. and (semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3 and laminat\$3).clm.	US-PGPUB	OR	OFF	2008/07/06 12:23
L12	8	"257".clas. and semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and melt\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:25
L13	30	"257".clas. and semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:26

L14	0	257/14,18,53,79,94,98,103.ccls. and (semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and laminat\$3 and melt\$3).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:30
L15	1	257/14,18,53,79,94,98,103.ccls. and (semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and laminat\$3 and melt\$3).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:30
L16	0	257/14,18,53,79,94,98,103.ccls. and (semiconduct\$3 adj laser and metal adj (layer film material) and over and under and active adj (layer film material) and resona\$5 adj cavity and laminat\$3 and melt\$3).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:31
L17	1	"257".clas. and (semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and laminat\$3 and melt\$3).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:31
L18	1	(semiconduct\$3 adj laser and metal adj (layer film material) and active adj (layer film material) and resona\$5 adj cavity and laminat\$3 and melt\$3).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/07/06 12:32

7/6/2008 1:05:37 PM

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